

# Taguchi methodology for the optimization of $n^+pp^+$ type silicon solar photovoltaic conversion efficiency.

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This study deals with  $n^+pp^+$  type crystalline silicon solar cells performances using the Taguchi method in its optimum. We; then, discuss physical parameters influence on efficiency solar cell, and also, we determine photovoltaic parameters of our structure by numeric simulation (PC1D).

Most previous work has used relatively low wafer resistivities (0.1-0.5 $\Omega$ cm). The modeling in this work showed that high efficiencies could also be achieved with 1.0  $\Omega$ cm in the p-region and the flexibility in front junction depth and back junction depth.

**Key words:** Taguchi methodology, numeric simulation (PC1D), solar cells, silicon, wafer resistivities,  $n^+pp^+$  structure, front junction depth, back junction depth, conversion efficiency.

## I – INTRODUCTION

The photovoltaic cells production with crystalline silicon represents the most dominant technology [1,2] compared to other technologies ( thin layers ). Nowadays, industrial priorities for high quality and lower investment cost require knowledge and quantification of every different physical material parameter influence level. Because of the great number of tests required, the use of classical method is fastidious and time consuming. To overcome this problem we propose in this paper to use the Taguchi method in its optimum [3, 4] to study  $n^+pp^+$  type silicon solar cells performances with thickness  $W=200\ \mu\text{m}$ , with following characteristics: cell area of  $1\text{cm}^2$ , front surface textured with inverted pyramids (angle  $54.74^\circ$ ), and rear surface no textured and antireflection layer is not used.

We studied material parameters influence on the efficiency conversion: Minority carrier diffusion length  $L_D$ , emitter sheet resistance  $R_{n+}$ , wafer resistivity  $R_p$ , back resistivity  $R_{p+}$ , front junction depth  $J_1$ , back junction depth  $J_2$ , front-surface recombination velocity  $S_F$  and back-surface recombination velocity  $S_R$ .

Photovoltaic parameters calculation is obtained by means of the software PC1D [5, 6], which solves the fully coupled time-dependent non-linear equations for the quasi-one-dimensional transport of electrons and the hole in crystalline semiconductor devices.

Most previous work has used relatively low wafer resistivities (0.1-0.5 $\Omega$ cm). The modeling in this

work showed that high efficiencies could also be achieved with 1.0  $\Omega$ cm material.

## II – TAGUCHI METHODOLOGY

This method consists of carrying out a series of organized and reduced tests according to a well defined logic.

### II-1 – Definition of features to study and of survey modes

The efficiency ( $\eta$ ) of a solar cell is deduced out of the three photovoltaic parameters: open-circuit voltage ( $V_{oc}$ ), short-circuit current ( $I_{sc}$ ) and fill factor (FF).

$$\text{It is given by: } \eta = FF \frac{V_{oc} I_{sc}}{P_i} \quad (1)$$

$P_i$  designates the incident power ( $P_i = 0.1\ \text{W/cm}^2$  under illumination AM1,5G) [7]

$$FF = \frac{P_{\max}}{V_{oc} I_{sc}} \quad (2)$$

### II-2 – Factors selection and their test values

We studied eight material parameters influence on the efficiency conversion: Minority carrier diffusion length  $L_D$ , emitter sheet resistance  $R_{n+}$ , wafer resistivity  $R_p$ , back resistivity  $R_{p+}$ , front junction depth  $J_1$ , back junction depth  $J_2$ , front-surface recombination velocity  $S_F$  and back-surface recombination velocity  $S_R$ . We took into consideration two levels for every material parameter. Values to test are collected in the table 1:

Factor	$L_D(\mu\text{m})$	$R_{n+}(\Omega/\square)$	$R_{p+}(\Omega/\square)$	$R_p(\Omega\text{cm})$	$J_1(\mu\text{m})$	$J_2(\mu\text{m})$	$S_F(\text{cm/s})$	$S_R(\text{cm/s})$
Level 1	150	50	50	0.1	0.1	0.1	$10^2$	$10^2$
Level 2	200	300	300	1.0	0.5	0.5	$10^7$	$10^7$

Table n°1 : Values to test of material parameters

**II-3 – Selection of the experience matrix to use**

The study of efficiencies of 8 factors each of them having two levels requires  $2^8$  in the traditional

approach. That's why we chose to use the reduced plans of Taguchi of type  $L_{16}$  (resolution IV) which require only 16 tests. The columns assignment is given in the following table 2:

Factors	$L_D$	$R_{p+}$	$R_p$	$J_2$	$J_1$	$R_{n+}$	$S_F$	$S_R$
Columns	1	2	4	7	8	11	13	14

Table n°2: Reduced plan of Taguchi of type  $L_{16}$  ( resolution IV)

Table of research of the interactions

The table n°3 was drawn up starting from the triangle of the interactions of the  $L_{16}$  table.

$L_D R_{p+}$	3	$L_D R_p$	5	$L_D J_2$	6	$L_D J_1$	9	$L_D R_{n+}$	10	$L_D S_F$	12	$L_D S_R$	15
$R_{p+} R_p$	6	$R_{p+} J_2$	5	$R_{p+} J_1$	10	$R_{p+} R_{n+}$	9	$R_{p+} S_F$	15	$R_{p+} S_R$	12		
$R_p J_2$	3	$R_p J_1$	12	$R_p R_{n+}$	15	$R_p S_F$	9	$R_p S_R$	10				
$J_2 J_1$	15	$J_2 R_{n+}$	12	$J_2 S_F$	10	$J_2 S_R$	9						
$J_1 R_{n+}$	3	$J_1 S_F$	5	$J_1 S_R$	6								
$R_{n+} S_F$	6	$R_{n+} S_R$	5										
$S_F S_R$	3												

Table n°3 : Triangle of the interactions of the  $L_{16}$  table

Alias table is given in the following table 4

In a resolution plan IV, the factors (order I) are alias with the order III interactions. Order II interactions are alias with other interactions of order II. Thus, we can consider that in a resolution plan IV, each factor is given without ambiguity (with the assumption that order III interactions are unimportant).

Action of the model	Columns	Alias
$L_D$	1	
$R_{p+}$	2	
$R_p$	4	
$J_2$	7	
$J_1$	8	
$R_{n+}$	11	

**II-4 – Tests results and factors middle effects calculation**

While applying the formula of middle effect calculation:

With  $\eta$  as the efficiency of the pattern, and  $\eta_{avg}$  the general average

Middle effect of factor A at the level I is:

$S_F$	13	
$S_R$	14	
$L_D R_{p+}$	3	$R_p J_2 + J_1 R_{n+} + S_F S_R$
$L_D R_p$	5	$R_{p+} J_2 + J_1 S_F + R_{n+} S_R$
$R_{p+} R_p$	6	$L_D J_2 + J_1 S_R + R_{n+} S_F$
$J_2 S_R$	9	$L_D J_1 + R_{p+} R_{n+} + R_p S_F$
$L_D R_{n+}$	10	$R_{p+} J_1 + R_p S_R + J_2 S_F$
$L_D S_F$	12	$R_{p+} S_R + R_p J_1 + J_2 R_{n+}$
$J_1 J_2$	15	$L_D S_R + R_{p+} S_F + R_p R_{n+}$

Table n°4: Alias table

$E_{Ai}$  = (Average of the  $\eta$  when A is at the level i) –  $\eta_{avg}$  (3)

Interaction of factor A at level I and factor B at level j is:

$I_{AiBj}$  = (Average of the  $\eta$  when A is at the level I and B at level j) –  $E_{Ai}$  –  $E_{Bj}$  –  $\eta_{avg}$  (4)

Effects of factors are collected in table 5:

Factor	$L_D$	$R_{n+}$	$R_{p+}$	$R_p$	$J_1$	$J_2$	$S_F$	$S_R$
$E_1$	-0.17	-0.05	-0.15	-0.03	-0.12	0.258	1.37	0.208
$E_2$	0.158	0.045	0.145	0.02	0.108	-0.27	-1.38	-0.22

Table n°5: Effects of factors

Effects of interaction between factor A and factor B are:

$$\begin{aligned}
 I(L_D R_{p+}) &= \begin{bmatrix} 0.015 & -0.005 \\ -0.013 & 0.017 \end{bmatrix} I(L_D R_p) \\
 &= \begin{bmatrix} -0.355 & 0.37 \\ 0.37 & -0.358 \end{bmatrix} \\
 I(R_{p+} R_p) &= \begin{bmatrix} 0.05 & -0.05 \\ -0.045 & 0.055 \end{bmatrix} I(J_2 S_R) \\
 &= \begin{bmatrix} 0.004 & 0.007 \\ 0.007 & 0.006 \end{bmatrix} \\
 I(L_D R_{n+}) &= \begin{bmatrix} 0.24 & -0.23 \\ -0.238 & 0.242 \end{bmatrix} I(L_D S_F) \\
 &= \begin{bmatrix} -0.08 & 0.095 \\ 0.095 & -0.083 \end{bmatrix} \\
 I(J_1 J_2) &= \begin{bmatrix} -0.568 & 0.585 \\ 0.585 & -0.568 \end{bmatrix}
 \end{aligned}$$

## II-5 – Results analysis and optimum configuration research

### II-5-1 – The next matrix pattern Survey

$$\begin{aligned}
 \eta &= \eta_{avg} + [E_1 \ E_2] [L_D] + [E_1 \ E_2] [R_{n+}] + [E_1 \ E_2] [R_p] + [E_1 \ E_2] [R_{p+}] + [E_1 \ E_2] [J_1] \\
 &\quad + [E_1 \ E_2] [J_2] + [E_1 \ E_2] [S_F] + [E_1 \ E_2] [S_R] + [L_D] [I_{AiBj}] [R_{p+}] + [L_D] [I_{AiBj}] [R_p] + [R_{p+}] [I_{AiBj}] [R_p] \\
 &\quad + [R_p] [I_{AiBj}] [R_{n+}] + [L_D] [I_{AiBj}] [S_F] + [J_1] [I_{AiBj}] [J_2] + [J_2] [I_{AiBj}] [S_R]
 \end{aligned} \quad (5)$$

$\eta_{avg}$  is the efficiency general means, [A] as indicator of level of the factor A and [I<sub>AiBj</sub>] as indicator of level of the interaction between factor A and factor B.

$$\eta_{avg} = \frac{1}{N} \sum_{i=1}^N \eta_i = 17.08 \%$$

(6)

Factor	L <sub>D</sub>	R <sub>n+</sub>	R <sub>p+</sub>	R <sub>p</sub>	J <sub>1</sub>	J <sub>2</sub>	S <sub>F</sub>	S <sub>R</sub>
S <sub>A</sub>	0.430	0.036	0.348	0.01	0.184	1.116	30.25	0.733
Interaction	L <sub>D</sub> R <sub>p+</sub>	L <sub>D</sub> R <sub>p</sub>	R <sub>p+</sub> R <sub>p</sub>	J <sub>2</sub> S <sub>R</sub>	L <sub>D</sub> R <sub>n+</sub>	L <sub>D</sub> S <sub>F</sub>	J <sub>1</sub> J <sub>2</sub>	
S <sub>AB</sub>	0.00018	0.579	0.0402	0.00085	0.902	0.123	5.267	

Table n°6: Squares sum of the factor and the interaction

To achieve a variance analysis we used a method called “regrouping” which consists of regrouping

N is the number of tests in the experiences scheme (N = 16).

First case: only the 1<sup>st</sup> order actions are considered. In this case, we take no account of interactions between factor A and factor B. It is simply to take the highest points effects of the factor, so that the theoretical efficiency of the pattern is maximized:  $\eta = 19.4 \%$

Second case: interactions are considered. When, we take account of interactions. We add the I<sub>AiBj</sub> element of matrix that have the highest value, the result got by the matrix model is:  $\eta_{model} = 20.73 \%$

### II-5-2 – Variance analysis

The squares sum of the factor A is:

$$S_A = (N/n_A) \sum (E_A)^2 \quad (7)$$

The squares sum of the interaction factor A and factor B is:  $S_{AB} = (N/(n_A n_B)) \sum (I_{AiBj})^2$  (8) N is the number of tests in the experiences scheme; n<sub>A</sub> is the number of factor A levels; and E<sub>A</sub> is the factor A effect.

$$S_{Total} = \sum S_A + \sum S_{AB} + S_{Residue}$$

(9)

$$\text{with } S_{Total} = \sum_{i=1}^{16} (\sum_l - \sum_{avg})^2 = 41.62$$

(10)

$$\text{and } \sum S_A + \sum S_{AB} = 40.02$$

(11)

$$\text{or } S_{Residue} = S_{Total} - \sum S_A - \sum S_{AB} = 1.6$$

(12)

S<sub>Residue</sub> is the residue squares sum.

The squares sum of the factor and the interaction are collected in table 6:

factors that apparently have no meaningful effects on residue (in our case it is the factor R<sub>p</sub>, R<sub>n+</sub>, R<sub>p+</sub>,

$J_1$  also interactions  $L_D R_{p+}$ ,  $R_{p+} R_p$ ,  $L_D S_F$  and  $J_2 S_R$ ), since the residue has a null degree of freedom ( $ddl=n_A-1$ ). We used Snedecor test [8] to compare

factor  $V_A$  variance and residual variance  $V_R$ . The test results are gathered in table 7.

Factor	S	ddl	Variance( $V_A$ )=S/ddl	$F_{\text{calculated}}(V_A/V_R)$	$F_{\text{theoretical}}$	Significant ?
$L_D$	0.430	1	0.430	1.65	5.12	no
$J_2$	1.116	1	1.116	4.29	5.12	no
$S_F$	30.25	1	30.25	116.35	5.12	yes
$S_R$	0.733	1	0.733	2.82	5.12	no
$L_D R_p$	0.579	1	0.579	2.23	5.12	no
$L_D R_{n+}$	0.902	1	0.902	3.45	5.12	no
$J_1 J_2$	5.267	1	5.267	20.26	5.12	yes
Residue	2.34	9	0.26			
$S_{\text{Total}}$	41.62	16				

Table n°7: Variance analysis

$F_{\text{theoretical}}(1,9)$  in this case is equal to 5.12 at a risk of 5% (Snedecor Table for  $p=0.95$ ).

The variance analysis showed that the factor  $S_F$  and interaction  $J_1 J_2$  are most significant. Don't forget that the interaction  $J_1 J_2$  is alias with interactions  $L_D S_R$ ,  $R_{p+} S_F$  and  $R_p R_{n+}$ .

The matrix pattern represents the system behavior to the grid nodes. In our case to have a maximum efficiency, it is necessary to place factors so that the system response is maximized.

First case: only the 1<sup>st</sup> order actions are considered

## II-6- The pattern interpretation and confirmation test

We will get the maximum when the factors reach levels given in table 8:

Factor	$L_D(\mu\text{m})$	$R_{n+}(\Omega/\delta)$	$R_{p+}(\Omega/\delta)$	$R_p(\Omega\text{cm})$	$J_1(\mu\text{m})$	$J_2(\mu\text{m})$	$S_F(\text{cm/s})$	$S_R(\text{cm/s})$
Levels	200	300	300	1.0	0.5	0.1	$10^2$	$10^2$

Table n°8 : Factors levels for the maximum of the efficiency (interactions not considered)

Second case: interactions are considered

The  $I_{Aij}$  element of matrix that have the highest value, which determine  $i$  or  $j$  level of factor. We deduce the following elements from previously calculated matrix:

$(L_D R_{p+})_{22}$ ,  $(L_D R_p)_{21}$ ,  $(R_{p+} R_p)_{22}$ ,  $(J_2 S_R)_{21}$ ,  $(L_D R_{n+})_{22}$ ,  $(L_D S_F)_{21}$  and  $(J_1 J_2)_{12}$  or  $(J_1 J_2)_{21}$ .

In this case incompatibilities exist with the results previously found. The interaction; then, compensates the factor effect. It is the case of the interaction  $L_D R_p$  which maximizes the efficiency when  $L_D = 200 \mu\text{m}$  and  $R_p = 0.1 \Omega\text{cm}$ , whereas while considering only the principal effects we had  $L_D = 200 \mu\text{m}$  and  $R_p = 1.0 \Omega\text{cm}$ . It is the same way in the case of  $J_1 J_2$  interaction which maximizes the efficiency when  $J_1 = 0.1 \mu\text{m}$  and  $J_2 = 0.5 \mu\text{m}$  or  $J_1 = 0.5 \mu\text{m}$  and  $J_2 = 0.1 \mu\text{m}$ , whereas while considering

only the principal effects we had  $J_1 = 0.5 \mu\text{m}$  and  $J_2 = 0.1 \mu\text{m}$ . But in the case of the interaction  $R_{p+} R_p$  which maximizes the efficiency when  $R_{p+} = 300 \Omega/\delta$  and  $R_p = 1.0 \Omega\text{cm}$ , this is the same result when only the 1<sup>st</sup> order actions are considered.

The analysis objective is to maximize the efficiency. To do so, it is necessary to make a total optimization while being based on the factors effects, interactions and matrix model.

The study of the matrix model gives us indeed the total optimum since the interaction  $J_1 J_2$  is more important regarding the effects factors of the  $J_1$  and  $J_2$ ; while being based on variance analysis, which raise the incompatibility mentioned previously.

The maximum of the efficiency is obtained for the following configurations:

Factor	$L_D(\mu\text{m})$	$R_{n+}(\Omega/\delta)$	$R_{p+}(\Omega/\delta)$	$R_p(\Omega\text{cm})$	$J_1(\mu\text{m})$	$J_2(\mu\text{m})$	$S_F(\text{cm/s})$	$S_R(\text{cm/s})$
Configuration1	200	300	300	0.1	0.1	0.5	$10^2$	$10^2$
Configuration2	200	300	300	0.1	0.5	0.1	$10^2$	$10^2$

Table n°9: Factors levels for the maximum of the efficiency (interactions are considered)

It is necessary to make a confirmation test. If the efficiency given by PC1D makes certain the hypothesis of the theoretical efficiency, the result got by PC1D is:

$\eta_{\text{PC1D}} = 21\%$  for configuration 1 and  $\eta_{\text{PC1D}} = 21.2\%$  for configuration 2

The theoretical efficiency of the pattern is:  $\eta_{\text{model}} = 20.68\%$  for the two configurations.

Our pattern is very satisfying, the efficiency is close to the predicted one.

In our model the maximum of the efficiency  $\eta_{\text{model}} = 20.73\%$  is obtained for the following configuration:

Factor	$L_D(\mu\text{m})$	$R_{n+}(\Omega/\delta)$	$R_{p+}(\Omega/\delta)$	$R_p(\Omega\text{cm})$	$J_1(\mu\text{m})$	$J_2(\mu\text{m})$	$S_F(\text{cm/s})$	$S_R(\text{cm/s})$
Configuration	200	300	300	1.0	0.1	0.5	$10^2$	$10^2$

Table n°10: Factors levels for the maximum of the efficiency in our model

The photovoltaic parameters got from these configurations are:

	$I_{\text{cc}}(\text{mA})$	$V_{\text{oc}}(\text{mV})$	$\eta_{(\text{PC1D})}$	$\eta_{\text{model}}$
Configuration 1	35.9	692.1	21 %	20.68%
Configuration 2	35.7	702.9	21.2 %	20.68%

Table n°11: Photovoltaic parameters

The corresponding characteristic I-V to these configurations is given in figure n°1. It shows a nearly oblong behavior.

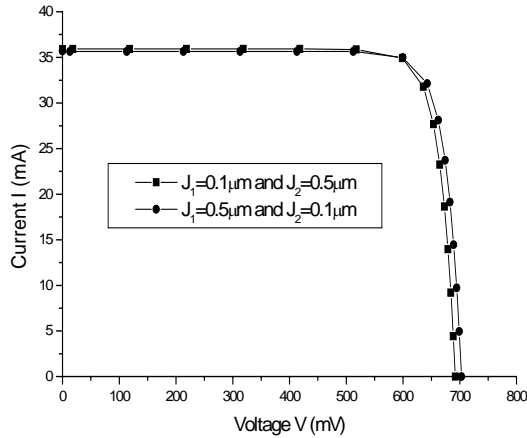


Figure n°1: Characteristic Current-Voltage for  $n^+pp^+$  cell with thickness  $W=200\mu\text{m}$ , diffusion length  $L_D=200\mu\text{m}$ ,  $0.1\Omega\text{cm}$  wafer resistivity,  $300\Omega/\delta$  emitter sheet resistance  $R_{n+}$  and  $300\Omega/\delta$  back resistivity  $R_{p+}$ .

### III – RESULTS AND DISCUSSION

#### III-1 Effect of wafer resistivity

Two different values of base doping concentration in the p-region are taken. They are  $2.3 \cdot 10^{17} \text{ cm}^{-3}$  ( $0.1 \Omega\text{cm}$ ) and  $1.5 \cdot 10^{16} \text{ cm}^{-3}$  ( $1.0 \Omega\text{cm}$ ). The modelling in this work showed that the difference in efficiency between the two different values of wafer resistivities, was very weak. We have  $\eta_{\text{model}} = 20.68\%$  and  $20.73\%$  for  $0.1 \Omega\text{cm}$  and  $1.0 \Omega\text{cm}$  respectively, as show in values of middle effect of factor E ( $R_p=0.1 \Omega\text{cm}$ )= $0.03$  and E ( $R_p=1.0 \Omega\text{cm}$ )= $0.02$ . We can conclude, that high efficiencies could also achieve with  $1.0 \Omega\text{cm}$  material. The present results concur well with result

of Catchpole et al [9] for a passivated emitter and rear cell (PERC) structure.

#### III-2 Effect of Back Surface Field

The efficiency improvement achievable through the use Back surface Field of  $n^+pp^+$  structure was significant. The improvement was  $1.63\%$  absolute from  $19.1\%$  of  $n^+p$  structure [10] to  $20.73\%$   $n^+pp^+$  structure. So that, the back surface doping concentration of  $n^+pp^+$  cell is more high than the base doping concentration in the p-region, of the sort than the minority carriers would be send back and than the effective recombination would be very weak.

The variance factor  $S_R$  (back-surface recombination velocity) is not significant, because the minority carriers diffusion length  $L_D=200\mu\text{m}$  in the base is not sufficiently large compared to the substrate  $W=200\mu\text{m}$ . But the variance factor  $S_F$  (front-surface recombination velocity) is very significant (with  $72\%$  level influence). So that, to increase solar cells performance, it is necessary to reduce the front-surface recombination velocity of the emitter  $S_F$  by the passivation method [11], while using, either deposition techniques of a thin oxide layer of  $60$  to  $100\text{\AA}$ , or by defects neutralization techniques and the hanging binding of surface by hydrogenation.

#### III- 3 Effect of interaction $J_1J_2$ .

Two different widths  $0.1\mu\text{m}$  and  $0.5\mu\text{m}$  were used for each junction (front junction  $J_1$  and back junction  $J_2$ ). The effect of interaction between factor  $J_1$  and factor  $J_2$  showed that  $I(J_1J_2)_{12}$  is equal to  $I(J_1J_2)_{21}$ , then we have the same efficiency in two cases  $[(J_1=0.1\mu\text{m}, J_2=0.5\mu\text{m})$  and  $(J_1=0.5\mu\text{m}, J_2=0.1\mu\text{m})]$ . From this result, we can conclude that pattern interpretation gives flexibility in the cell design.

#### III-4 Comparison with PERC and PERL (see table n°12)

The best laboratory efficiency for single crystal silicon is today 24.7% [12]. This efficiency can

only be realized with very elaborate technology.

	$n^+pp^+$ (this work)	PERC [9]	PERL [12]
Textured frond surface	yes	Yes	yes
Textured rear surface	no	Yes	yes
Antireflection coating	no	Yes	yes
Efficiency $\eta$ %	21.2	21.8	24.7

Table n°12

The efficiency difference is 3.5% absolute for our cell and Passivated Emitter and Rear Locally diffused (PERL) cell structure, this difference is attributed to the local  $p^+$ -doped BSF ( back surface field) in PERL structure. And also the program PC1D has not the possibility to create a layer with the local  $p^+$ -doped.

If we compare our work with PERC cell structure, the difference in efficiency is small (0.6% absolute), although we have not used antireflection coating layer and textured rear surface. It's absolutely certain that the combination of textured surface and antireflection coating contributed to improving efficiency.

#### IV- CONCLUSION

On one hand, the efficiency of  $n^+pp^+$  structure is always higher than its conventional  $n^+p$  solar cell due to the back surface field. On the other hand, the Taguchi method used this work showed that  $n^+pp^+$  structure allows a large degree of flexibility in cell designing and manufacturing for two reasons. The first is that high efficiency could also be achieved with 1.0  $\Omega\text{cm}$  material. The second then there is little difference in the efficiencies for both cases [ $(J_1=0.1\mu\text{m}, J_2=0.5\mu\text{m})$  and  $(J_1=0.5\mu\text{m}, J_2=0.1\mu\text{m})$ ]. From these results, we can conclude that the Taguchi method allows manufacturing engineers to have the flexibility in cell designing.

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